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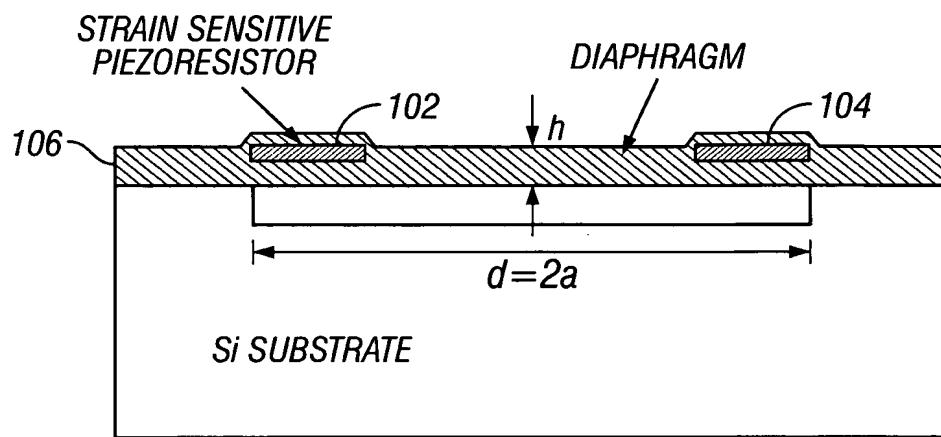


FIG. 1

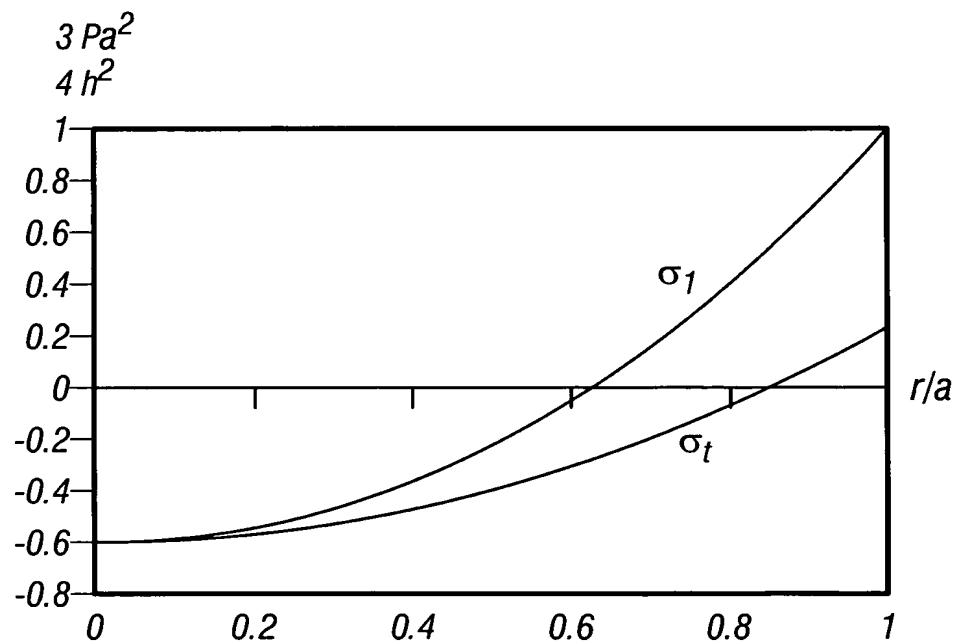
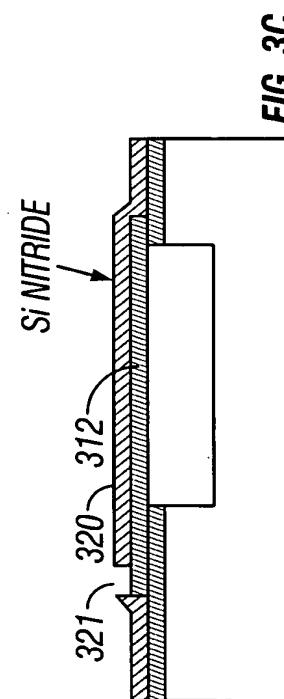
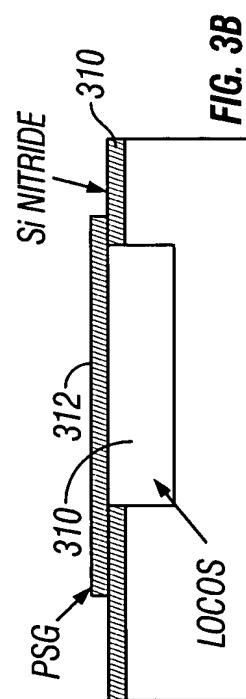
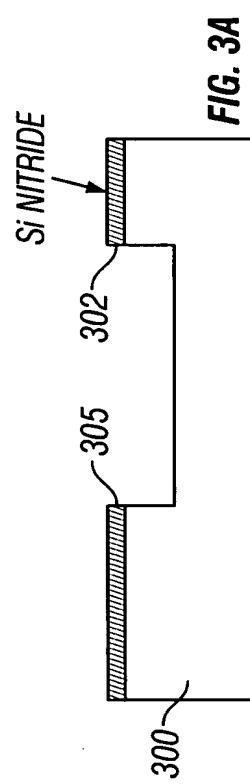
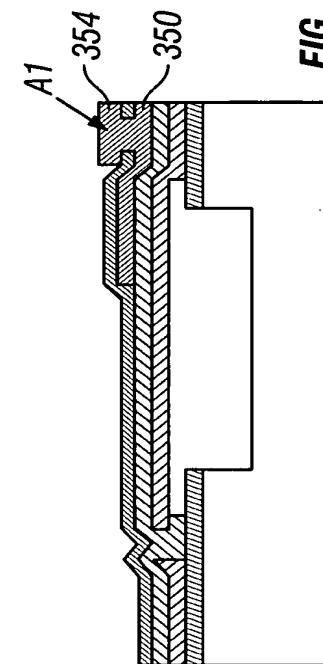
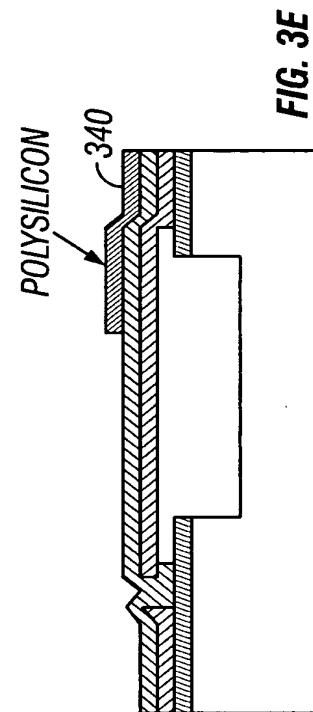
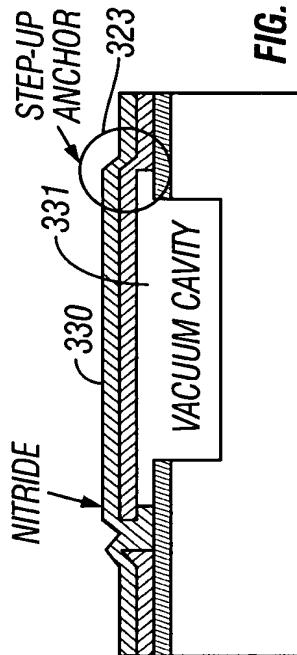


FIG. 2



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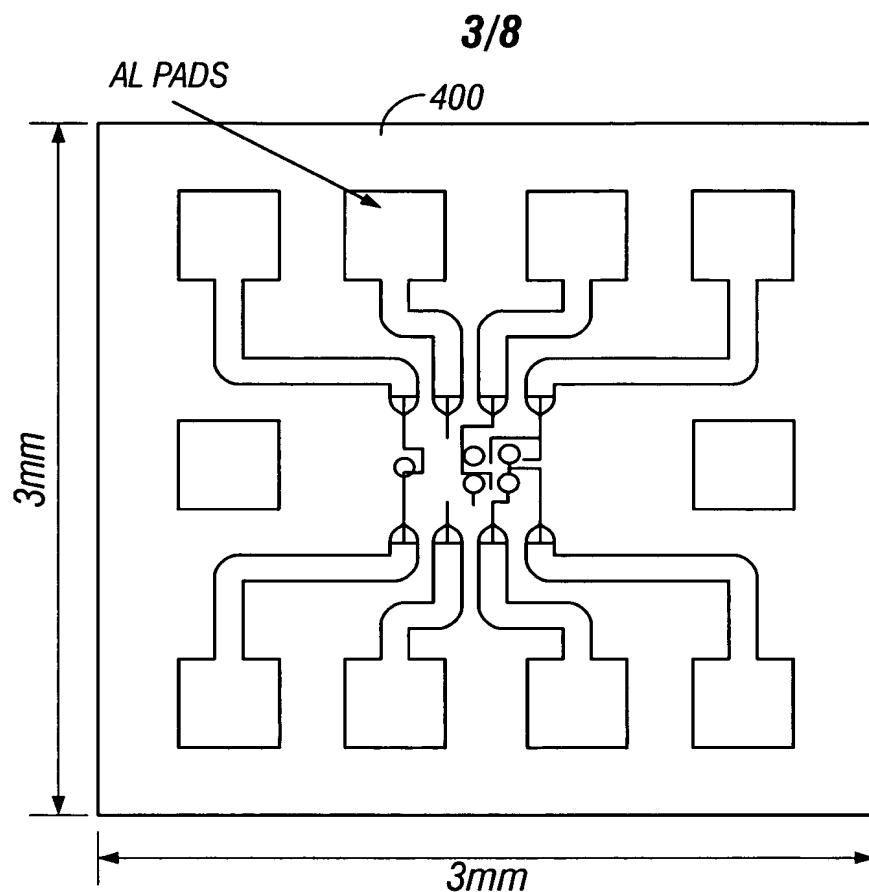


FIG. 4

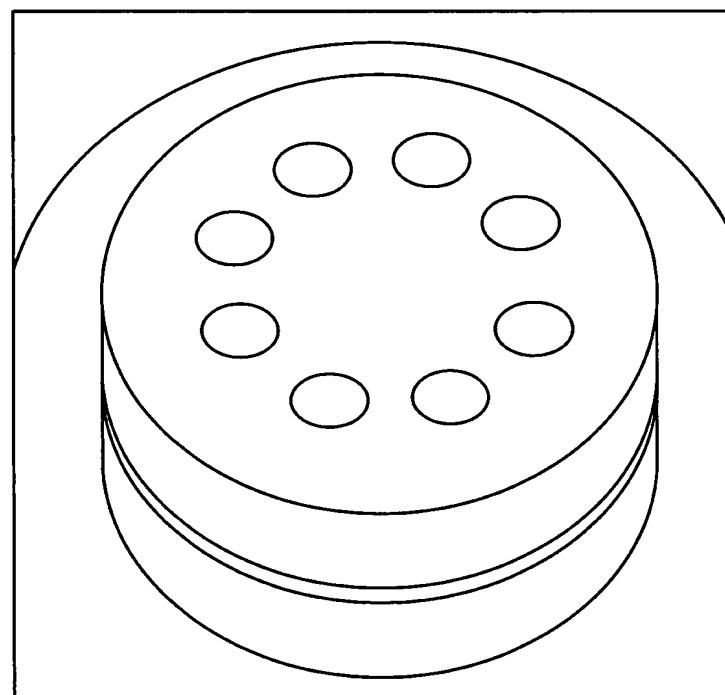


FIG. 5

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HIGH PRESSURE APPLICATION

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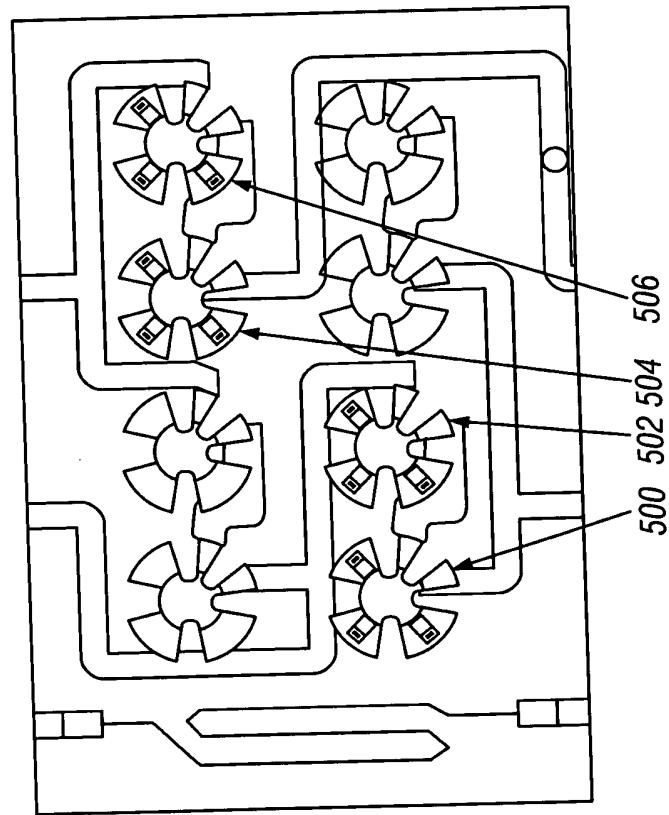
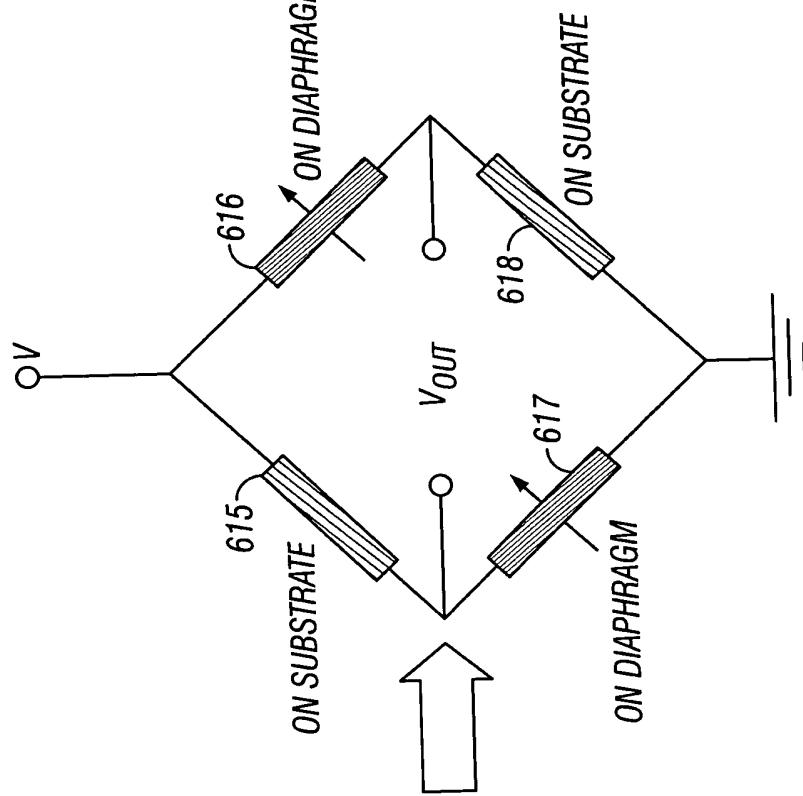


FIG. 6

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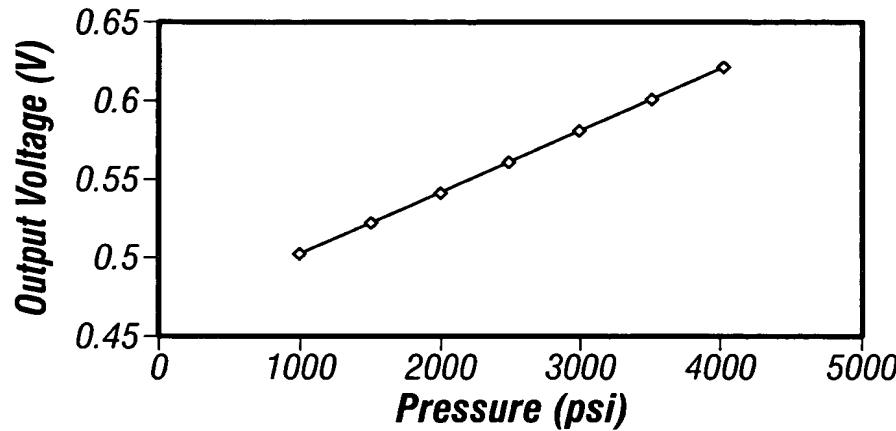


FIG. 7

STEP-UP ANCHOR:
CAUSED BY
THE EDGE OF
SACRIFICIAL LAYER

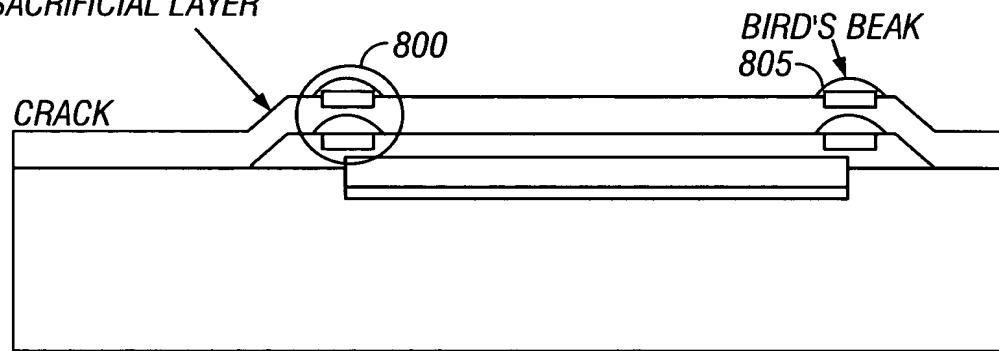


FIG. 8

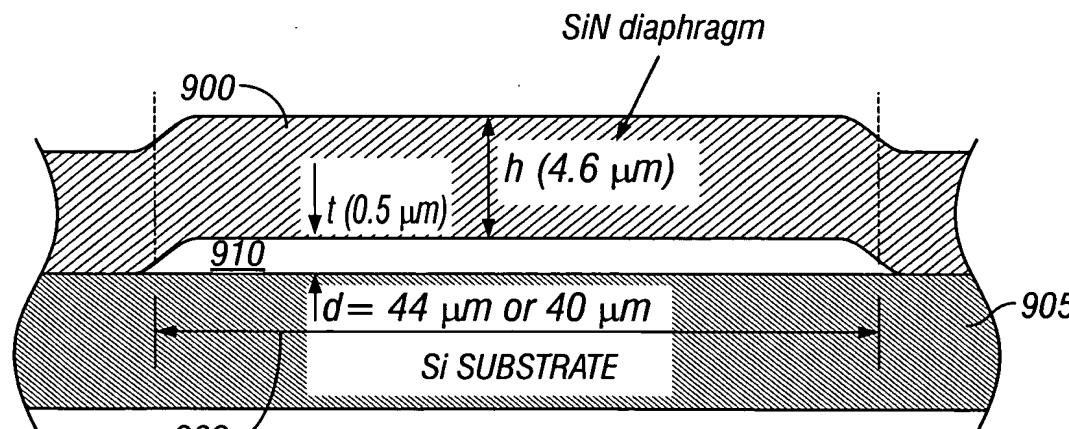


FIG. 9

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FIG. 10D

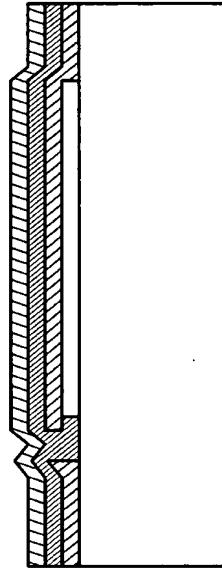


FIG. 10E

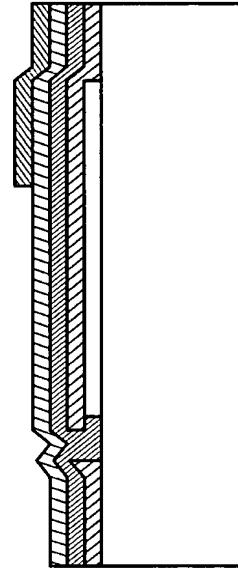


FIG. 10F

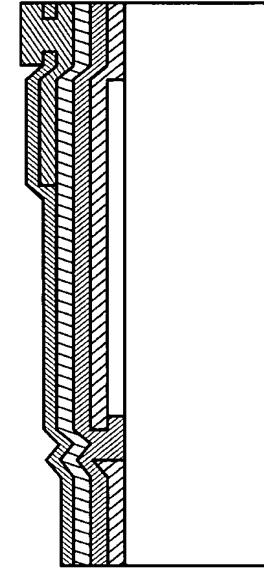


FIG. 10A

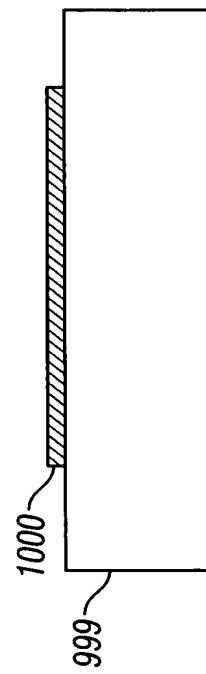


FIG. 10B

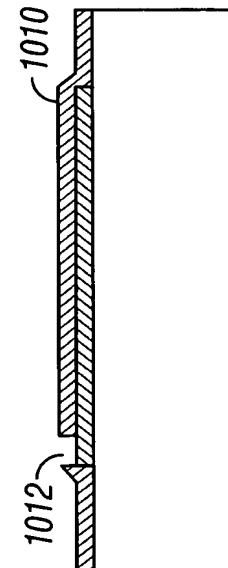
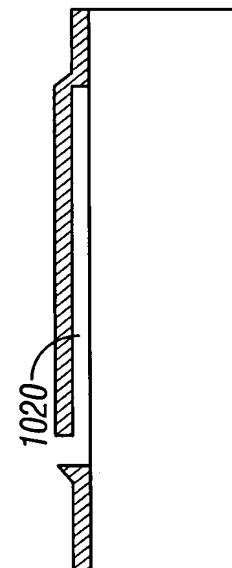


FIG. 10C





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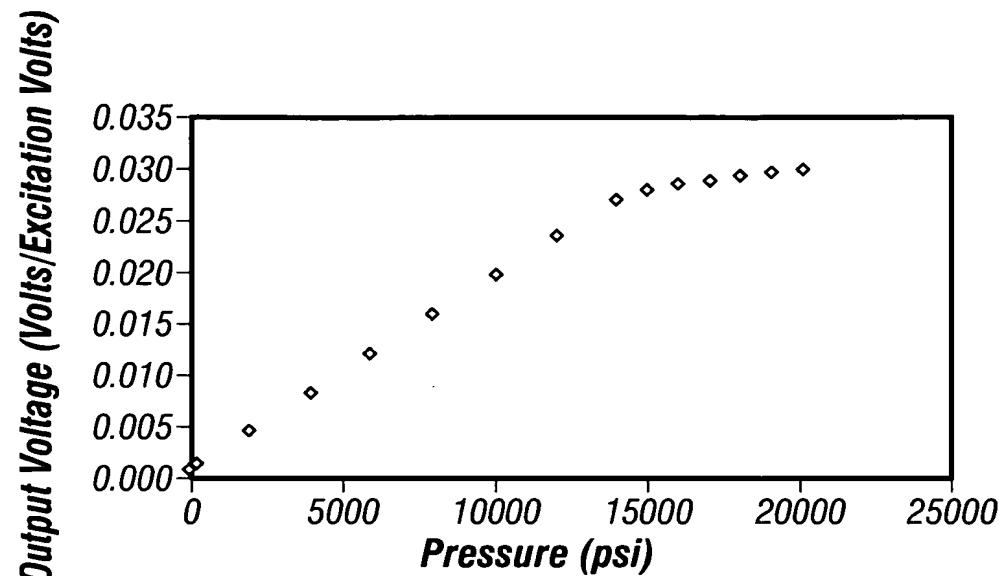


FIG. 11

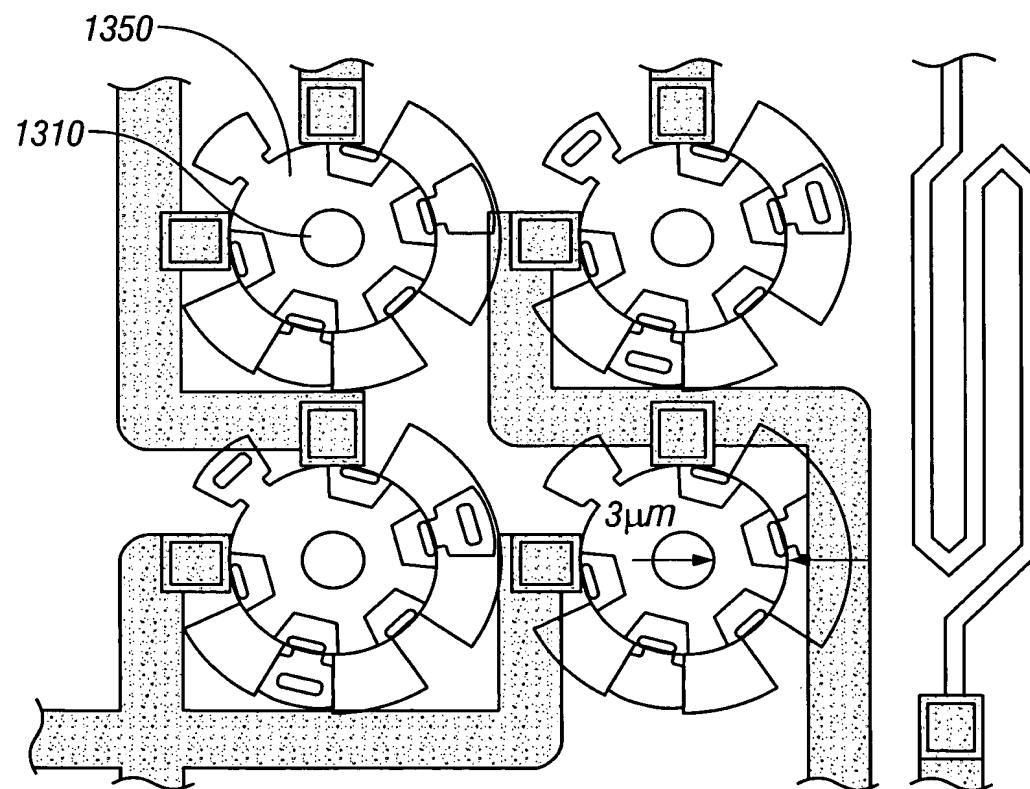


FIG. 12

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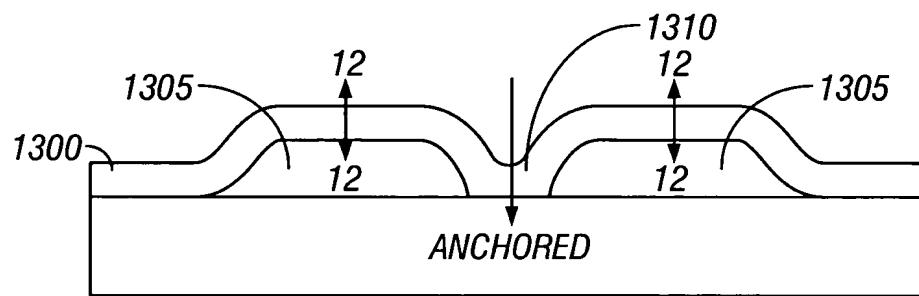


FIG. 13